Datemiter

As a below named inventor, I declare: that I verily believe myself to be the original, first and sole (if only one individual inventor is listed below) or an original, first and joint inventor (if more than one individual inventor is listed below) of the invention in

PROFILE MEASURING METHOD AND MEASUREMENT APPARATUS USING INTERFERENCE OF LIGHT

the specification of which is attached hereto unless the following box is checked.

	was filed on			ted States	App	lication
_	or PCT International	Application	No		·	and
	was amended on		(if	applicable.).	

I hereby state that I have reviewed and understand the contents of the above identified specification, including the claims, as amended by any amendment referred to above.

I acknowledge the duty to disclose information of which is material to patentability as defined in 37 CFR 1.56.

I hereby claim foreign priority benefits under 35 U.S.C. 119(a)-(d) or 365 (b) of any foreign application(s) for patent or inventor's certificate, or 35 U.S.C. 365(a) of any PCT International application which designated at least one country other than the United States, listed below and have also identified below any foreign application for patent or inventor's certificate, or PCT International application having a filing date before that of the application on which priority is claimed:

Country	Category	Application No.	Filing Date	Claim
Japan	Patent	2001-267786	September 4, 2001	Yes

I hereby appoint the registrants of Oblon, Spivak, McClelland, Maier & Neustadt, P.C., Fourth Floor, 1755 Jefferson Davis Highway, Arlington, Virginia 22202, Customer No. 22850, or any one of them. Send correspondence to Oblon, Spivak, McClelland, Mailer & Neustadt, P.C., Fourth Floor, 1755 Jefferson Davis Highway, Arlington, Virginia 22202, Telephone No. (703) 413-3000.

I declare further that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

DECLARATION FOR PATENT APPLICATION

I declare further that my citizenship, residence and mailing address are as stated below next to my name:

Inventor: (Signature)	<u>Date</u>	Residence and mailing address
Masaaki Adachi Masaaki Adachi	Date: February 15, 200	2 53-6, Wakamatsu-machi, Kanazawa-shi, Ishikawa-ken, Japan
	Date: Citizen of: Japan	
	Date:	
	Citizen of: Japan Date:	· · · · · · · · · · · · · · · · · · ·
	Citizen of: Japan	
	Date: Citizen of: Japan	
	Date: Citizen of: Japan	
	Date:	
	Citizen of: Japan	<u> </u>
	Date: Citizen of: Japan	

DOCKET NO.: 220102US2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Masaaki ADACHI

SERIAL NO.: NEW APPLICATION

FILED: HEREWITH

FOR: PROFILE MEASURING METHOD AND MEASUREMENT APPARATUS USING

INTERFERENCE OF LIGHT

REQUEST FOR SMALL ENTITY STATUS

This application qualifies for small entity status.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND, MAIER & NEUSTADT, P.C.

Marvin J. Spivak

Registration No. 24,913

C. Irvin McClelland Registration Number 21,124

Date: 3/1/02



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